

Correction

Correction to “Minimizing Scanning Errors in Piezoelectric Stack-Actuated Nanopositioning Platforms”

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Owing to an error in the final phase of submitting the publication-ready document of the original paper [1], the figures appearing in the

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published version do not have the intended axis labels. The correct labels are as follows.

- In Figure 1(b): dL, dH, dHA, and rA should be read as ΔL , ΔH , $\Delta H = \frac{(\pm \frac{\Delta L}{2})^2}{2H}$, and $r = \frac{a+b}{a}$, respectively.
- In Figure 4: Int, Plant, Controller, and o should be read as $C_2(s)$, $G_{xx}(s)$, $C_1(s)$, and y_m , respectively.
- In Figures 2, 6, 8, 11, 12(a), 12(b), 13, 14, 15, and 16: mm should be read as μm .
- In Figures 3, 9, and 10: Mag(dB) should be read as Mag ($\mu\text{m}/\text{V}$ in dB).

REFERENCES

- [1] S. S. Aphale, B. Bhikkaji, and S. O. R. Moheimani, “Minimizing scanning errors in piezoelectric stack-actuated nanopositioning platforms,” *IEEE Trans. Nanotechnol.*, vol. 7, no. 1, pp. 79–90, Jan. 2008.